**SEM - FEI NanoSEM**

Scanning Electron Microscope - FEI NanoSEM Nova 230

- **Description**
  
  The *FEI Nova NanoSEM 230* high resolution field emission SEM is our main imaging tool for nanoparticles, featuring 1nm resolution at 15 KV. A STEM II detector and a vCD detector (for beam deceleration imaging) have recently been added to the standard ETD and TLD detectors. Equipped with a JC Nability Nanometer Pattern Generation System (NPGS 9.0) this NanoSEM can write patterns down to 20 nm feature sizes.

- **Configuration**
  
  - Detectors: TLD, ETD, vCD, & STEM-II
  - Beam deceleration sample stage bias
  - High Speed Beam Blanker
  - NPGS 9 Beamwriting software

- **Training**
  
  Users may request training

- **Location**
  
  SEM Lab: ESB28B

- **Contact**
  
  Qiti Guo